

Supporting Information

Surface Functional Groups Modification Induced Partial Fermi level

Pinning and Ohmic Contact at Borophene-MoS₂ Interfaces

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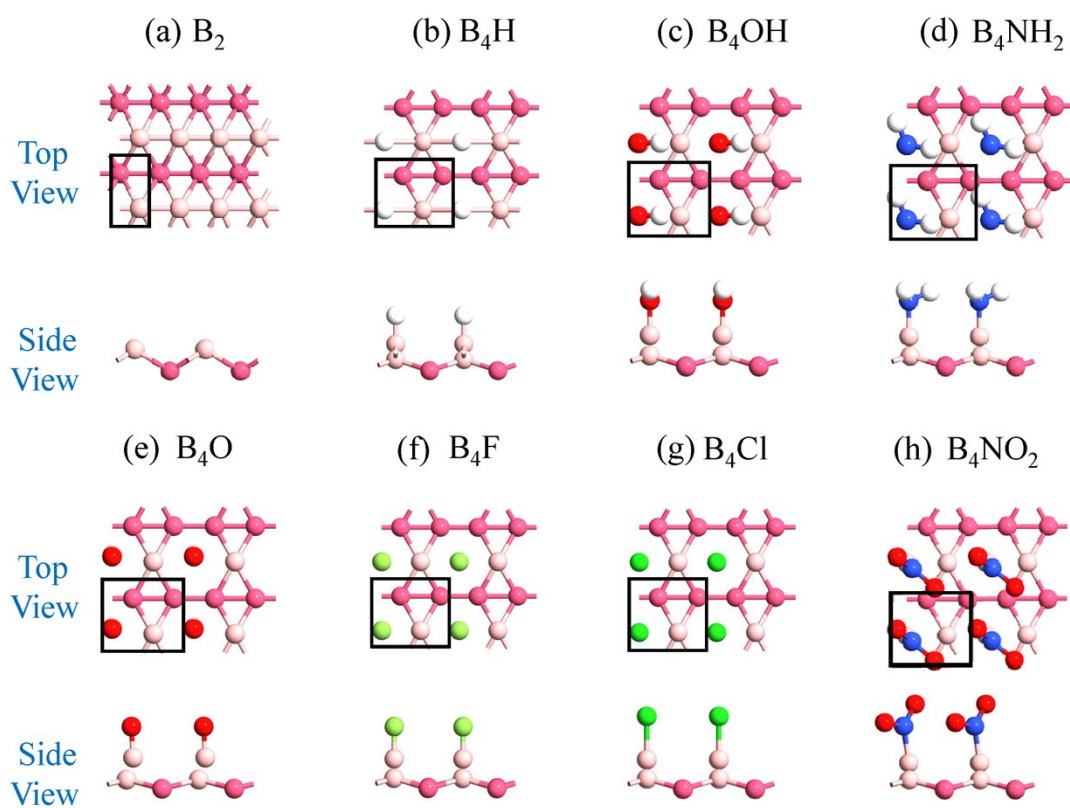


Fig. S1. Top view and side view of the most structures of monolayer (a) B₂, (b) B₄H, (c) B₄OH, (d) B₄NH₂, (e) B₄O, (f) B₄F, (g) B₄Cl, (h) B₄NO₂.

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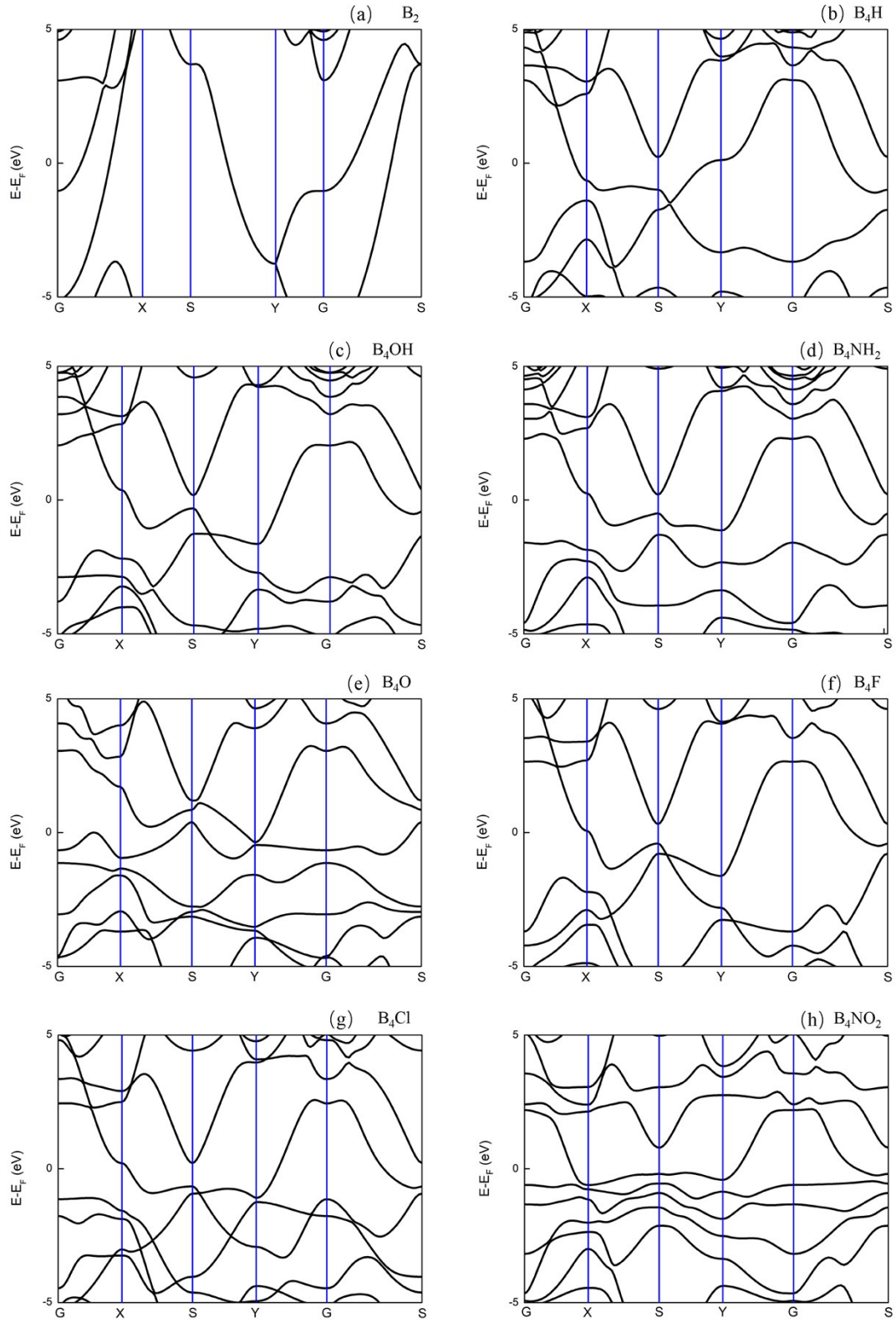


Fig. S2. Band structures of monolayer (a) B_2 , (b) B_4H , (c) B_4OH , (d) B_4NH_2 , (e) B_4O , (f) B_4F , (g) B_4Cl , (h) B_4NO_2 .

	B ₄ H/MoS ₂	B ₄ OH/MoS ₂	B ₄ NH ₂ /MoS ₂	B ₄ O/MoS ₂	B ₄ F/MoS ₂	B ₄ Cl/MoS ₂	B ₄ NO ₂ /MoS ₂
$E_{Initial_1}$ (eV)	-102.746	-118.743	-128.775	-108.843	-106.201	-101.370	-132.321
$E_{Initial_2}$ (eV)	-102.700	-118.718	-128.742	-108.847	-106.173	-101.340	-132.316

Fig. S3. Side view and the total energy of two initial stacking patterns of the B₄X/MoS₂ systems (X = H, OH, NH₂, O, F, Cl, NO₂).

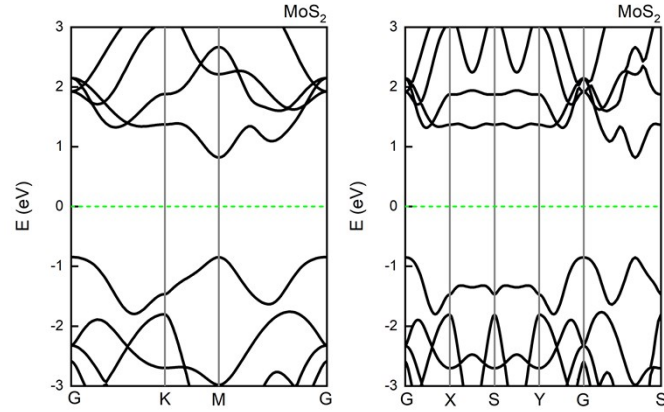


Fig. S4. Band structures of isolated ML MoS₂ in *k*-point path G→K→M→G and path G→X→S→Y→G→S.

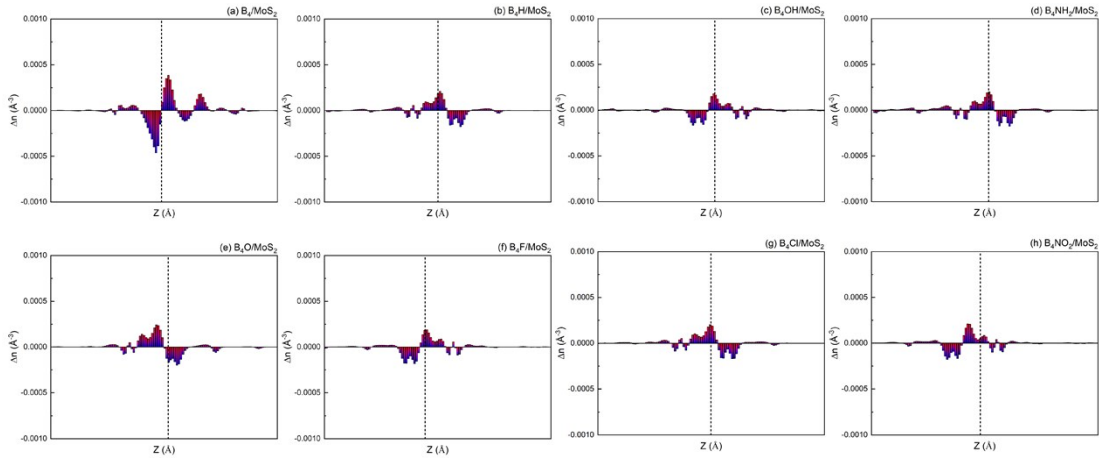


Fig. S5. Plane averaged electron density difference ($\Delta n = n_{device} - n_{electrode} - n_{channel}$) along the Z-direction of the MoS₂ transistors with different electrical contacts. Where, $n_{electrode}$, $n_{channel}$ and n_{device} are the plane-averaged electron density of isolated borophene-based metal electrode, isolated MoS₂ channel, and entire transistor device, respectively. The positive/negative values represent the charge accumulation/depletion, respectively. The dotted lines represent interfaces D.